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S.N. 09/975,540

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Chang et al.

Group Art Unit: 1746

Serial No.: 09/975,540

Examiner: Markhoff, A.

Filed: 10/10/2001

In Response to Office Action
Dated: 12/18/2003

For: A METHOD AND APPARATUS FOR REDUCING ACIDIC CONTAMINATION ON
A PROCESS WAFER FOLLOWING AN ETCHING PROCESS

Attorney Docket No.: 67,200-526

Certificate of Mailing

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Date: March 17, 2004

Kathy Dixon

RESPONSE TO OFFICE ACTION

Commissioner for Patents
Alexandria, VA 22313-1450

Dear Sir:

In response to an Office Action mailed 12/18/2003,
please enter the following amendments and consider the following
remarks.